

Notice of References Cited	Application/Control No. 10/807,425	Applicant(s)/Patent Under Reexamination SASAKI ET AL.	
	Examiner Paul D. Kim	Art Unit 3729	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,470,565	10-2002	Sasaki, Yoshitaka	29/603.12
*	B	US-6,301,079	10-2001	Hanamoto et al.	360/236.5
*	C	US-5,841,608	11-1998	Kasamatsu et al.	360/236.6
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	K	US-			
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	N	JP 07029120 A	01-1995	Japan	YANAGISAWA et al.	G11B 05/31
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	U	"Floating thin film head fabricated by ion etching method"; Nakanishi, T.; Kogure, K.; Toshima, T.; Yanagisawa, K.; Magnetics, IEEE Transactions on Volume 16, Issue 5, Sep 1980; Pages:785 - 787.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.